SERIAL NO. FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE ATTY.DOCKET NO. (Modified) PATENT AND TRADEMARK OFFICE 06336P USA INFORMATION DISCLOSURE **APPLICANT** Aaron Scott Lukas, et al. STATEMENT BY APPLICANT (Use several sheets if necessary) FILING DATE GROUP 1762 (37 CFR 1.98(b)) **U.S. PATENT DOCUMENTS** FILING DATE IF APPRO-PRIATE DOCUMENT NUMBER DATE NAME CLASS SUBCLASS 10/3/1995 J. S. Shor, et al. 204 129.3 9/1/1993 5 5 6 0 9 4 3/28/2000 J. Yang, et al. 430 296 1/8/1999 4 6 2 0 312.8 0 5 6 4/25/2000 T. W. Mountsier 428 6/22/1998 6 2 8 7 427 3 5 5/29/2001 T. W. Mountsier 574 3/16/2000 5 5/18/1998 6 2 8 4 0 0 9/4/2001 J. Shi, et al. 118 715 5/26/1999 6 3 1 2 7 9 3 11/6/2001 A. Grill, et al. 428 312.6 6 4 7 5 9 3 0 11/5/2002 K. H. Junker, et al. -438 787 1/31/2000 01 0 2 8/30/2001 1/29/2001 0 8 1 9 A. Shiota, et al. 428 447 01 0 0 3 8 9 1 9 11/8/2001 I. L. Berry, III, et al. 428 446 3/19/2001 02 0 446 0 2 4 1 8/1/2002 428 7/16/2001 1 3 Q. Han, et al. 02 0 C 6 5 0 0 8/8/2002 R. Albano, et al. 428 304.4 9/14/2001 1 03 0 0 3 2 3 0 0 2/13/2003 C. Waldfried, et al. 438 725 5/14/2001 R. Albano, et al. 03 9/14/2001 0 0 5 3/20/2003 FOREIGN PATENT DOCUMENTS DOCUMENT NUMBER TRANSLATION DATE COUNTRY CLASS SUBCLASS YES EP Maeda eta 0 3 2 5 Sept-2000 Europe X wo 0 Jan 2000 World PCT X 0 0 2 2 4 WO 0 2 9 Jan 2002 World 0 7 1 1 PU X wo 0 02 5 3 World Pot X 6 5 4 aug 2002 OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) A. Hozumi, et al., "Low-Temperature Elimination of Organic Components from Mesostructured Organic—Inorganic Composite Films Using Vacuum Ultraviolet Light, Chem. Mater. 2000, 12, 3842-3847. no month M. Ouyang, et al., "Conversion of Some Siloxane Polymers to Silicon Oxide by UV/Ozone Photochemical Processes, Chem Mater. 2000, 12, 1591-1596. (no month, but published on Web May 2000) A. Hozumi, et al., "Micropatterned Silica Films with Ordered Nanopores Fabricated through Photocalcination, National Institute of Advanced Industrial Science & Technology, Volume 1, Number 8, August 2001. T. Clark, Jr., et al., "A New Application of UV-Ozone Treatment in the Preparation of Substrate-Supported, Mesoporous Thin Films, Chem Mater. 2000, 12, 3879-3884. no month, butout on web. Dec. 2000 Q. Han, et al., "Ultra Low-k Porous Silicon Dioxide Films from a Plasma Process," IEEE (2001), pp. 171-173. C. Waldfried, et al., "Single Wafer RapidCuring™ of Porous Low-k Materials," IEEE (2002), pp. 226-228. DATE CONSIDERED **EXAMINER**

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PTO/SB/08A (08-03)

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Application Number 10/624,		
	356	
INFORMATION DISCLOSURE Filing Date July 21	July 21, 2003	
STATEMENT BYCAPPEICANT First Named Inventor Aaron	Scott Lukas, et al.	
(Use as many sheets as necessary) Art Unit 1762		
MAY 3 1 2005 Examiner Name M. L	Padgett	
Sheet 1 Attorney Docket Number 06336P	USA	

U. S. PATENT DOCUMENTS						
Examiner Initials*	Cite No.1	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
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1.00	,	Country Code ³ Number ⁴ Kind Code ⁵ (7			Relevant Figures Appear	Т ⁶
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		WO 2005/019303	03-03-2005	Ree, et al.		1
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				Application Number	10/624,356	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Filing Date	July 21, 2003	
				First Named Inventor	Aaron Scott Lukas, et al.	
			essary)	Art Unit	1762	
				Examiner Name		
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MAP		DIXIT, Girish, et al., "Film Properties and Integration Performance of a Nano-Porous Carbon Doped Oxide", Applied Materials, Inc, Santa Clara, California, USA, International Interconnect Technology Conference, June 2004	>				
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